

Fig.3

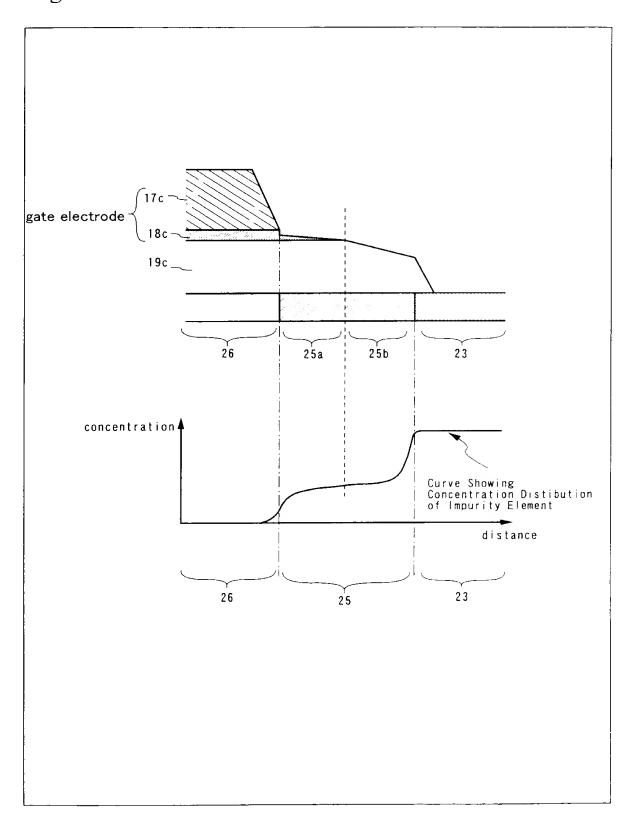
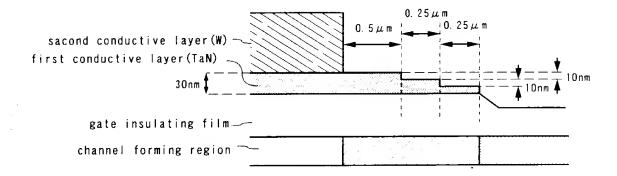


Fig.4



Schematic Structual View in Simulation

Fig. 5

_____ P Conc. [/cm3]

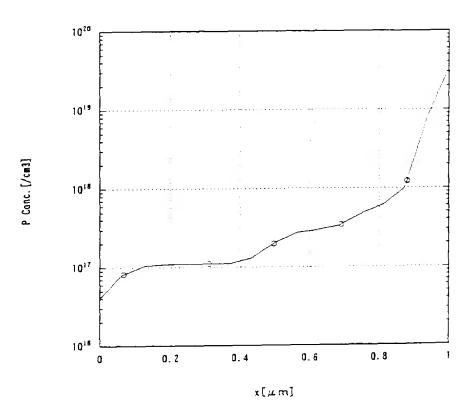
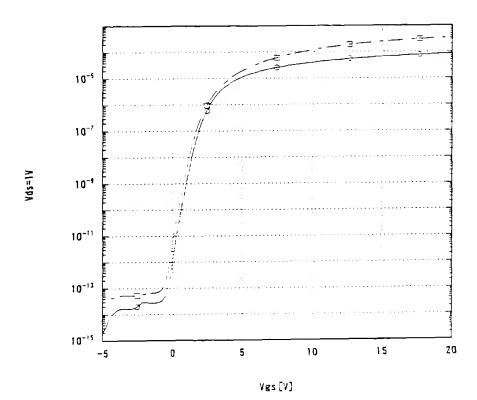
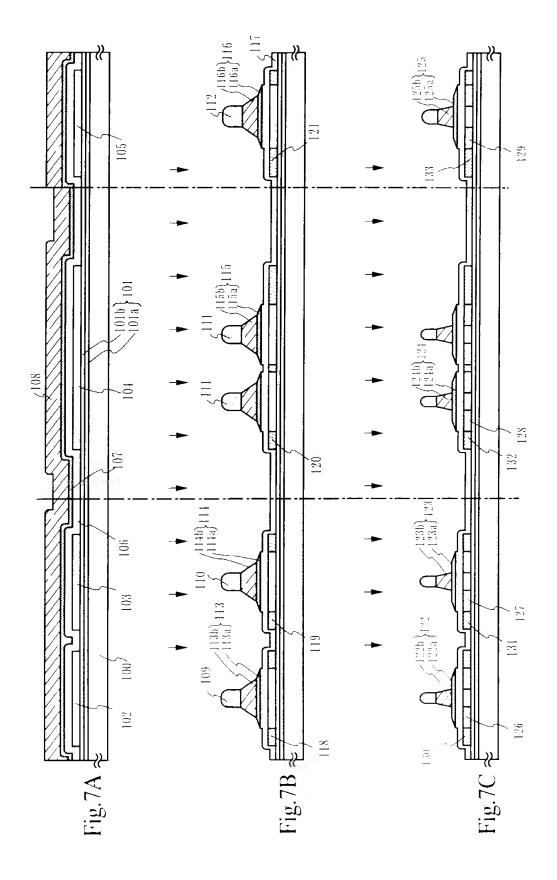


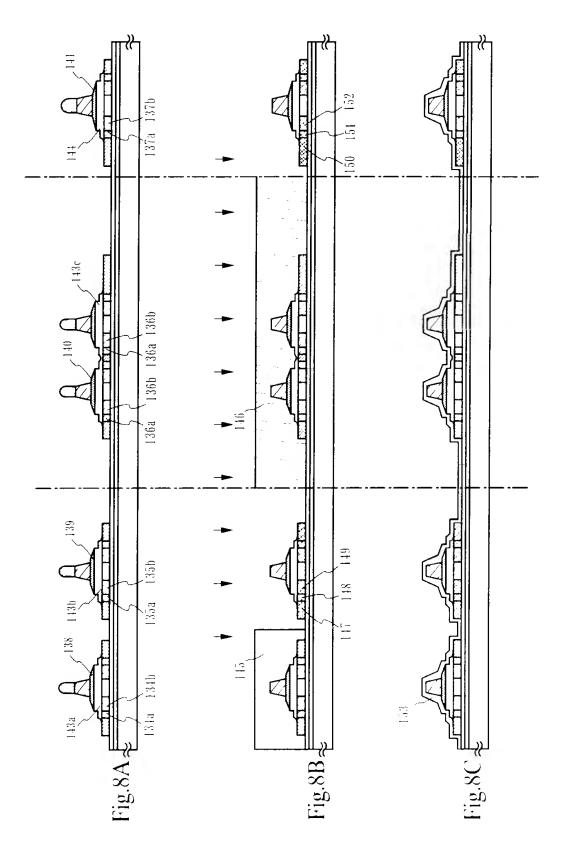
Fig. 6

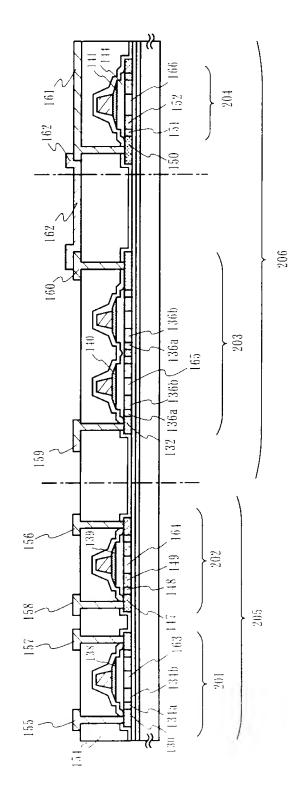
--- Vds=1V

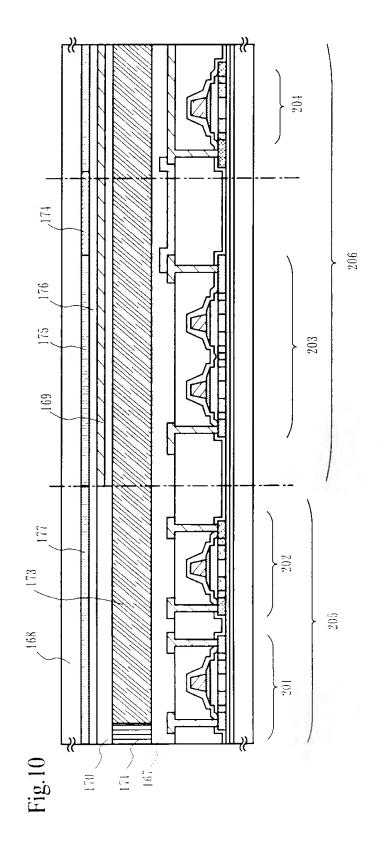
--- Vds=14V











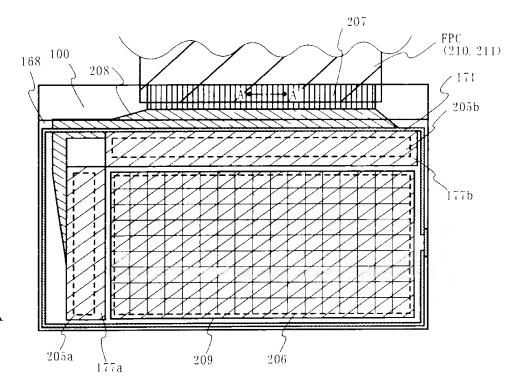
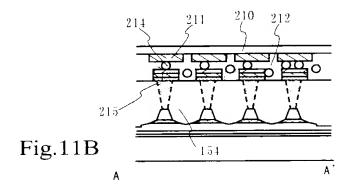
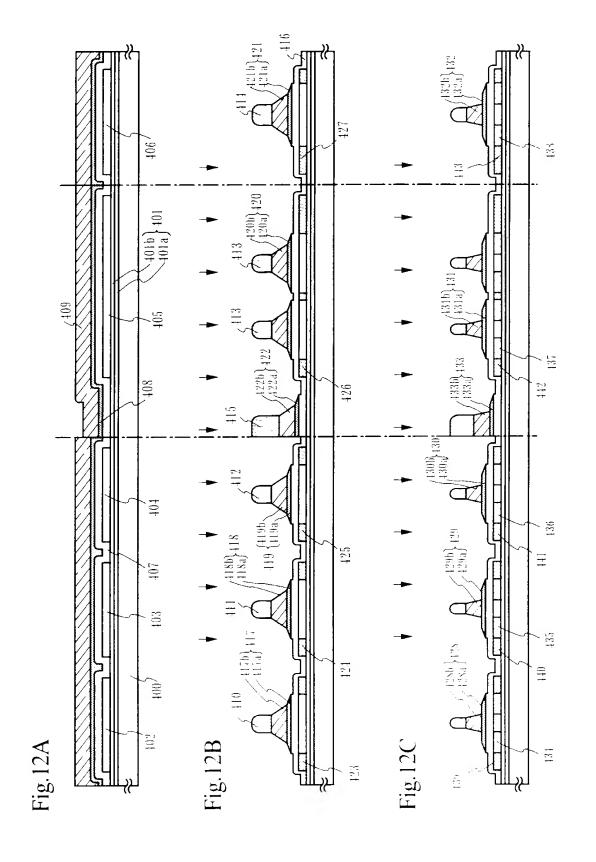
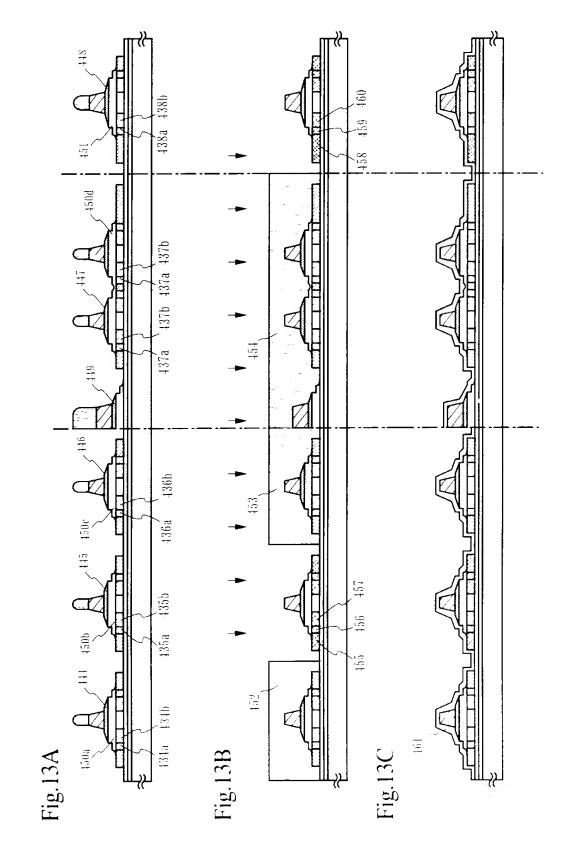


Fig.11A







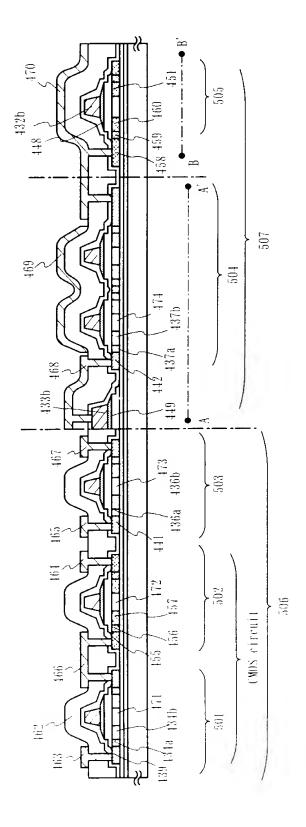
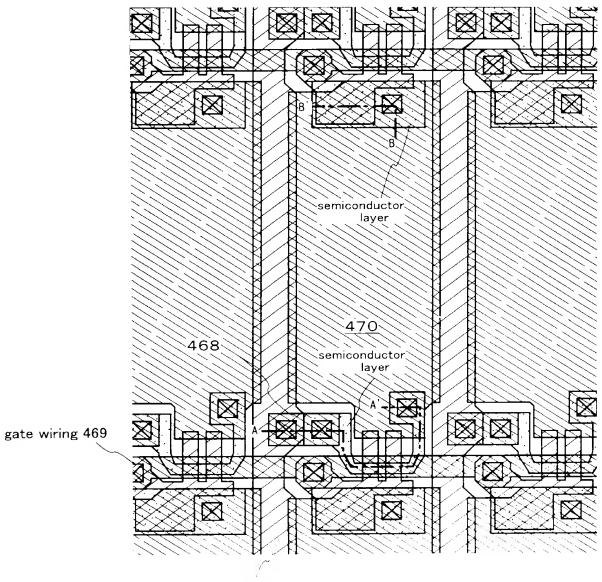


Fig.15



source wiring 433b.449

Fig.16

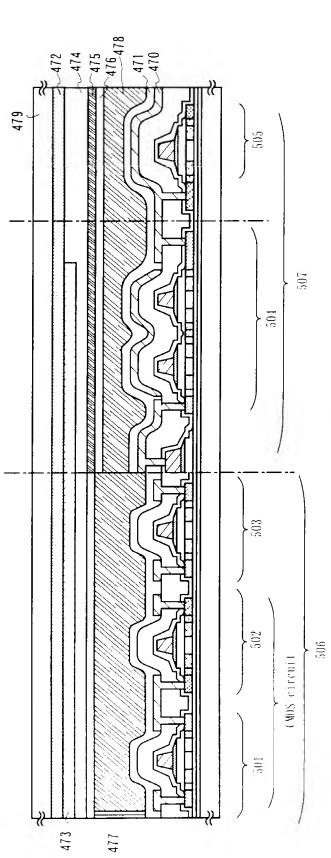
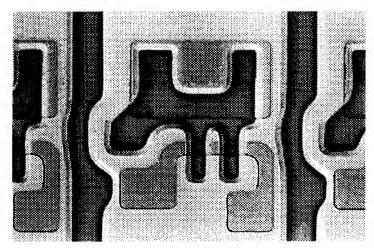


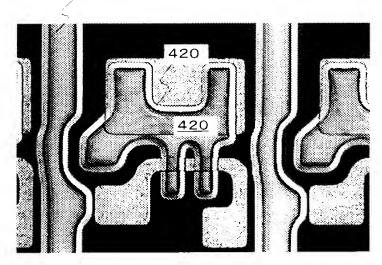
Fig. 17A



ICP power: 500W, RF power: 150W, chamber pressure: 1.0Pa $Cl_2=25sccm$, $CF_4=25sccm$, $O_2=10sccm$

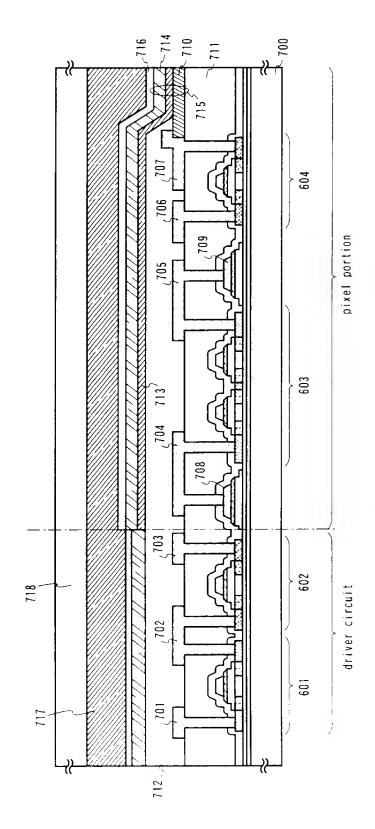
Fig.17B

422



ICP power: 500W, RF power: 20W, chamber pressure: 1.0Pa Cl_2 =30sccm, CF_4 =30sccm

Fig. 18



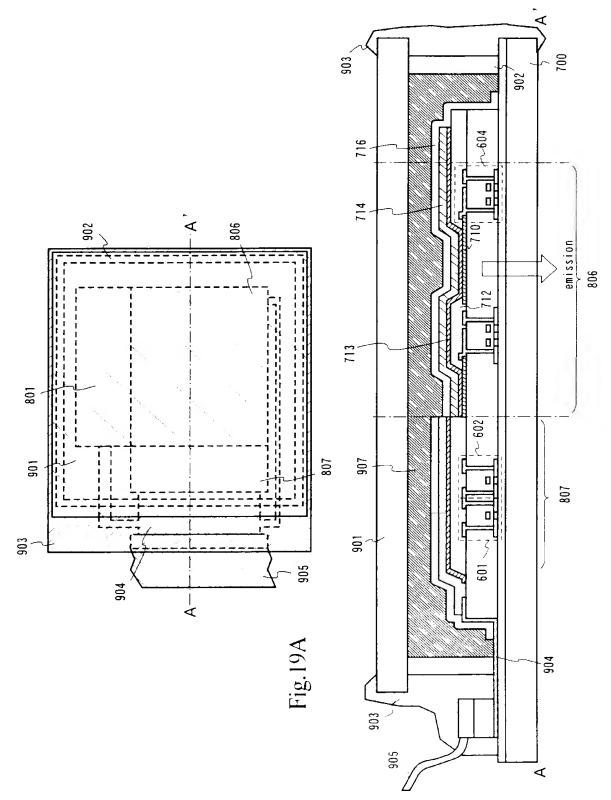
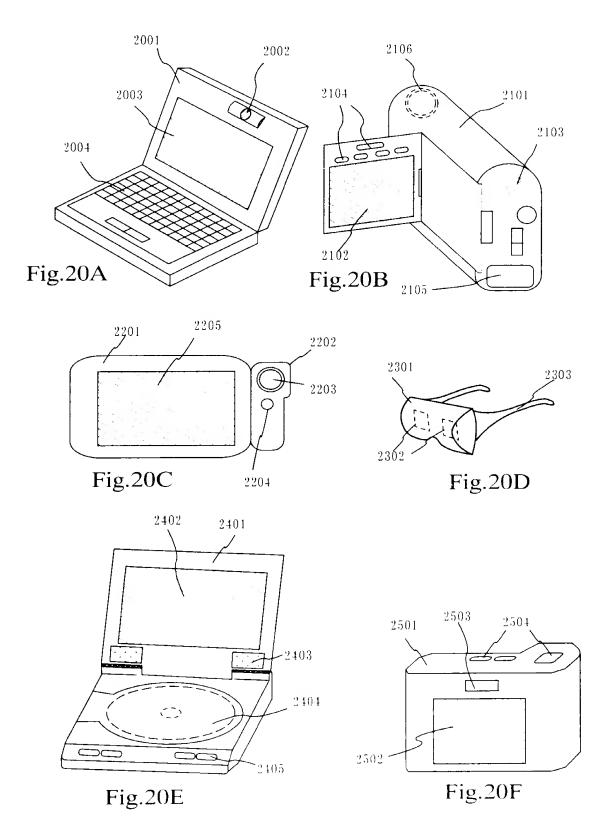


Fig.19B



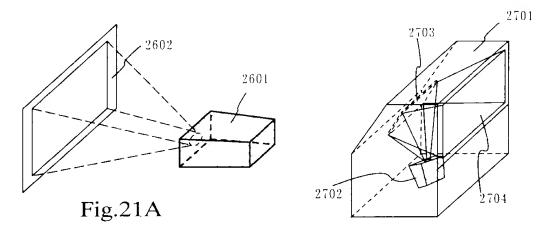
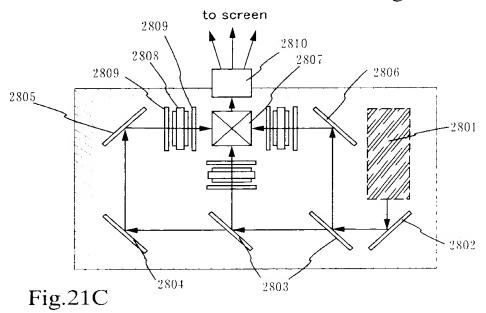


Fig.21B



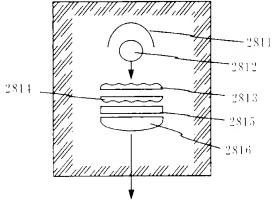
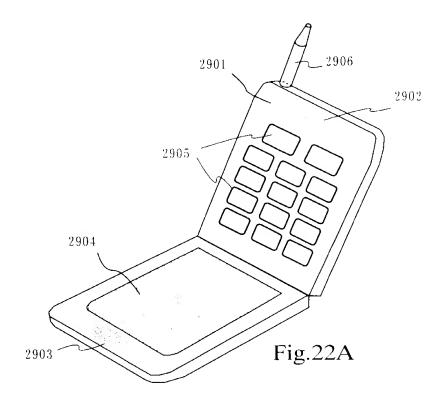
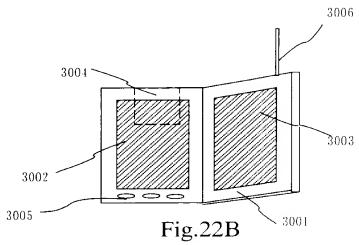
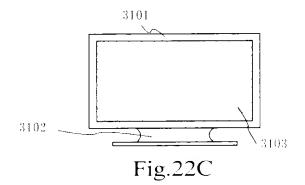


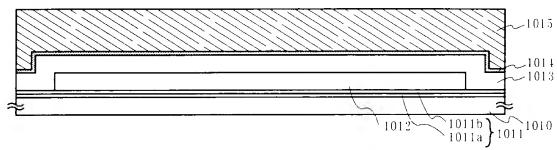
Fig.21D

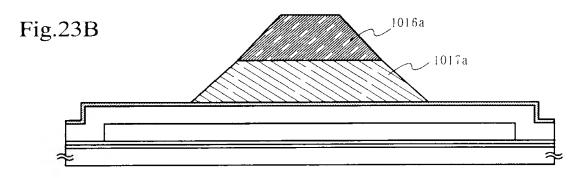


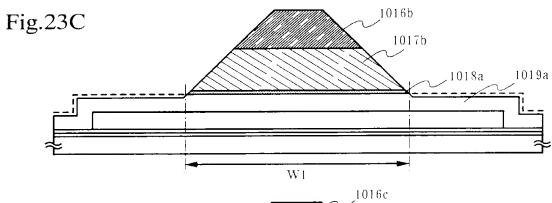












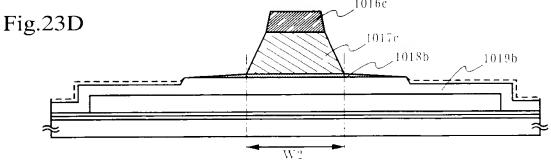
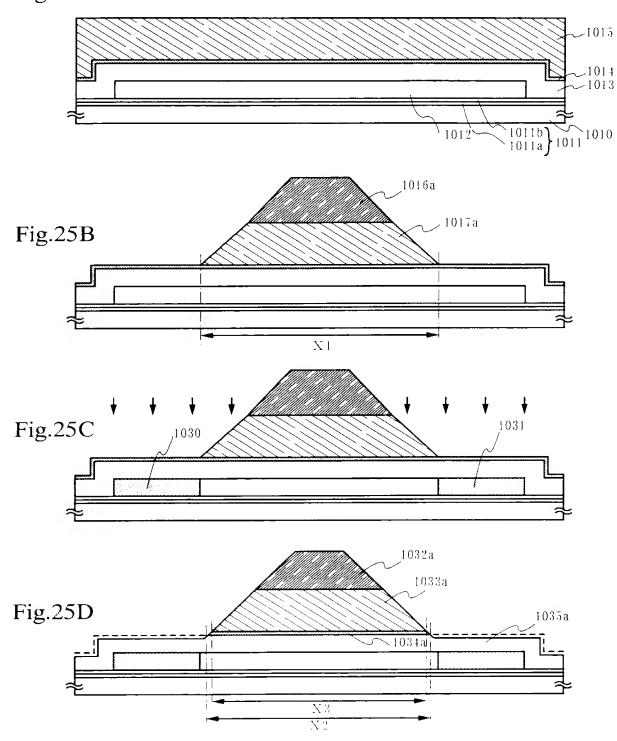
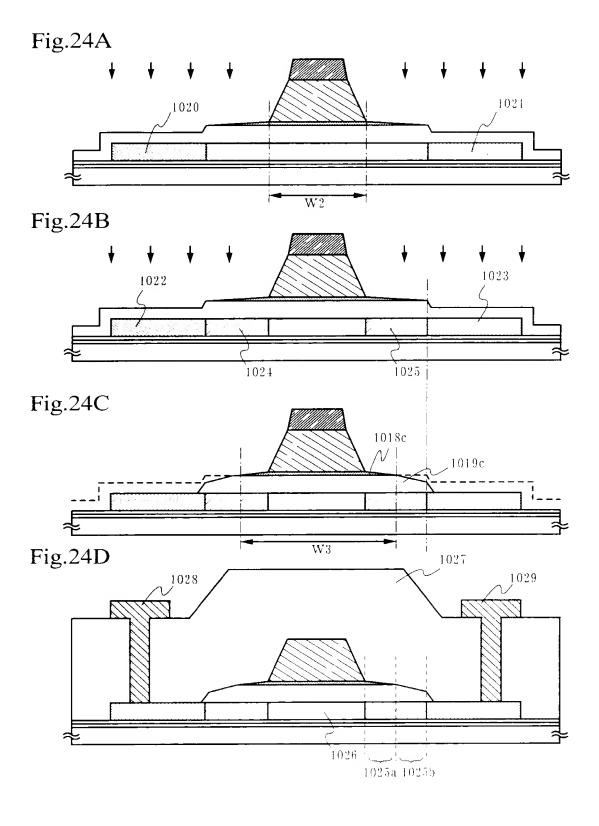
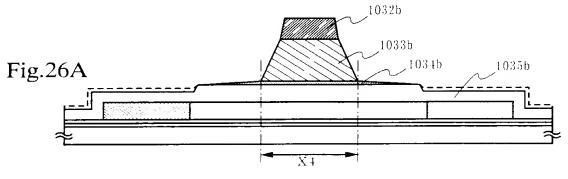
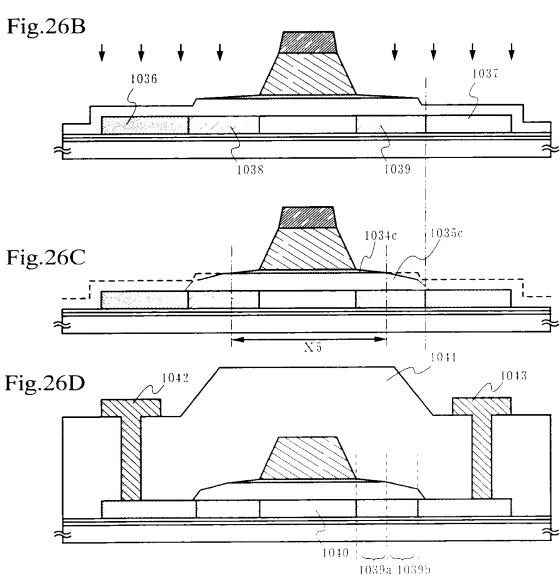


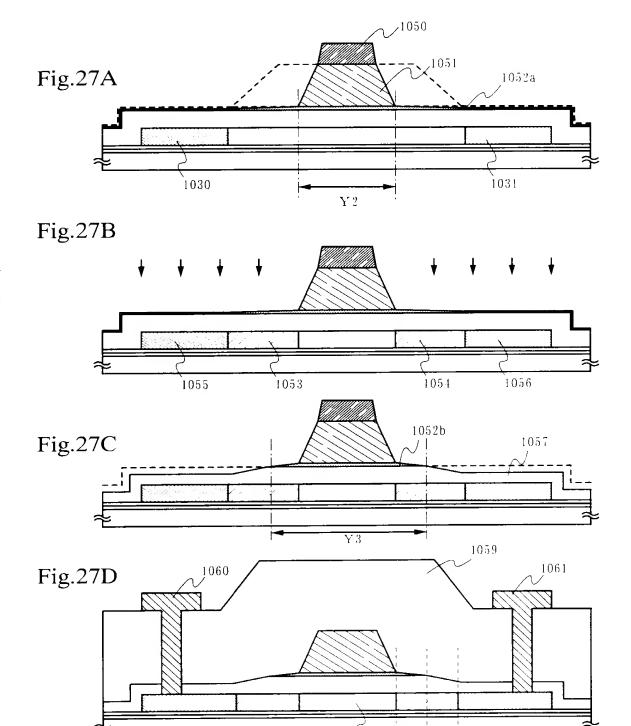
Fig.25A



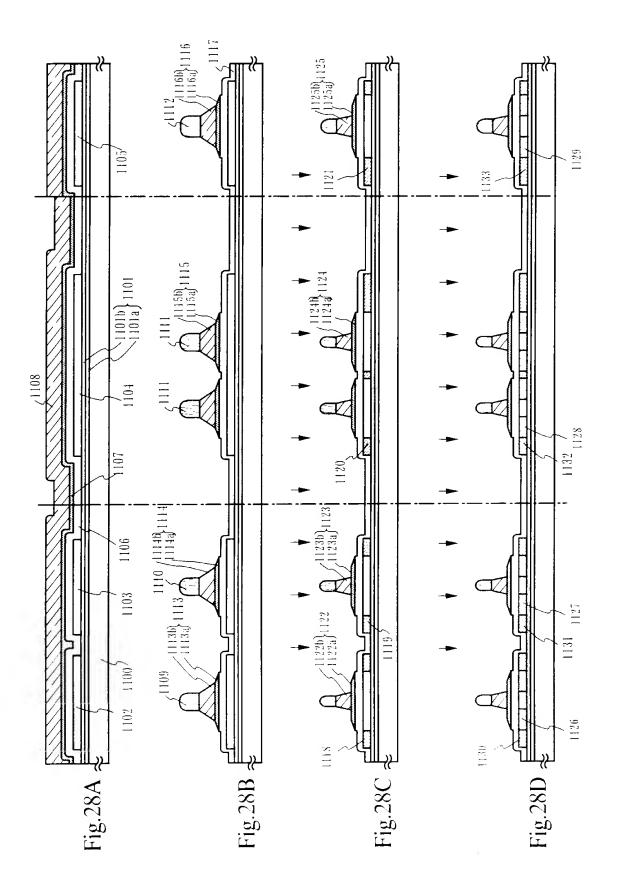








1058 · _____. 1054a 1054b



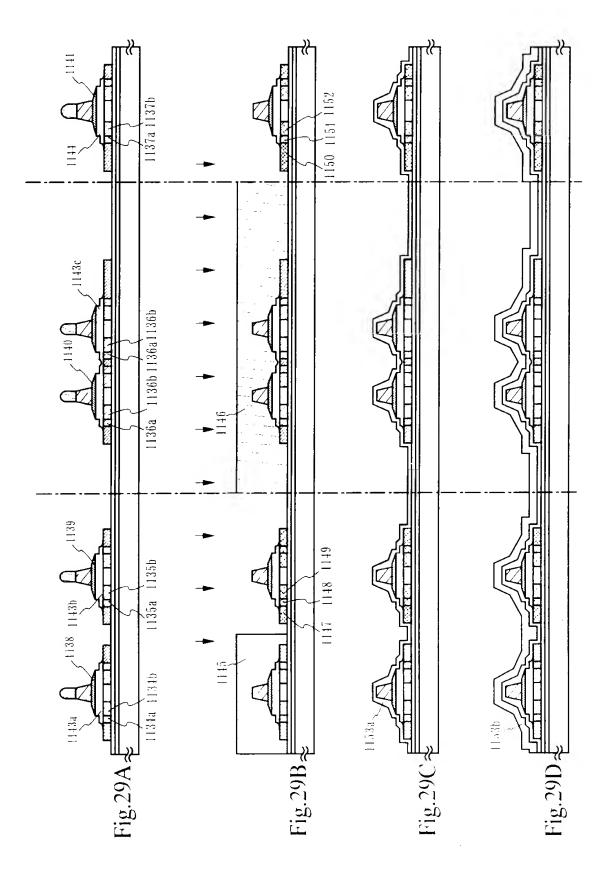
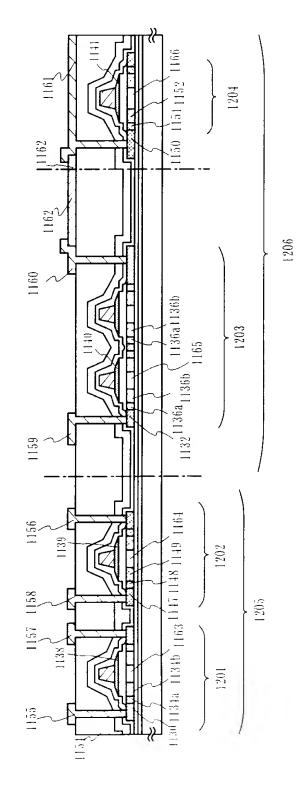
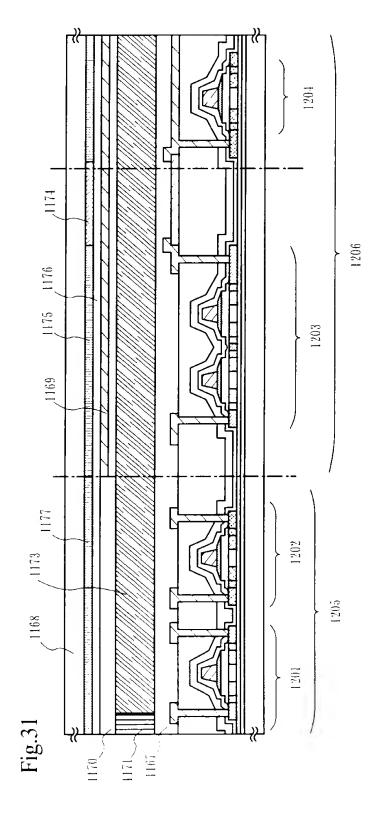


Fig.30





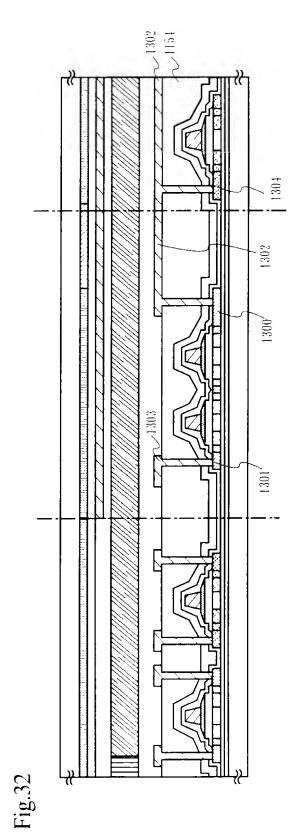


Fig.33

